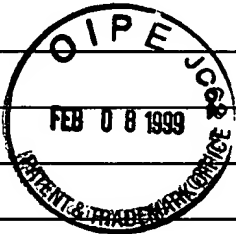


U.S. Department of Commerce, Patent and Trademark Office					Docket No.		Serial No.	
					APPM/3049		09/206,027	
<b>LIST OF RELEVANT ART CITED BY APPLICANT</b> (Use several sheets if necessary)					Applicant			
					Cohen, et al.			
					Filing Date		Group	
					December 4, 1998		Unknown	



U.S. Patent Documents							
*Examiner Initial		Document Number	Issue Date	Name	Class	Subclass	Filing Date If Appropriate
LV	AA	5,660,682	08/26/1997	Zhao, et al.	438	715	
	AB						
	AC						
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	AI						
	AJ						
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Foreign Patent Documents							Translation	
		Document Number	Date	Country	Class	Subclass	Yes	No
	AL							
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	AN							
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	AP							

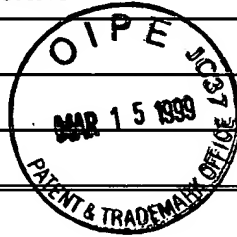
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)	
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		Filing Date	Group
		December 4, 1998	Unknown



## U.S. Patent Documents

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	AA						
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## Foreign Patent Documents

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LV	AQ	Yasushi Sawada, Hiroshi Tamaru, Masuhiro Kogoma, Motoaki Kawase, and Kenji Hashimoto, "The Reduction of Copper Oxide Thin Films With Hydrogen Plasma Generated By An Atmospheric-Pressure Glow Discharge," J. Phys. D: Appl. Phys. 29 (1996), pp. 2539-2544.
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